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(12) **United States Design Patent** (10) **Patent No.:** **US D860,419 S**  
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(54) **ELECTRIC FURNACE FOR SUBSTRATE PROCESSING APPARATUS**

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(71) Applicant: **KOKUSAI ELECTRIC CORPORATION**, Tokyo (JP)

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(72) Inventors: **Tetsuya Kosugi**, Toyama (JP); **Hitoshi Murata**, Toyama (JP); **Masaaki Ueno**, Toyama (JP)

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(73) Assignee: **KOKUSAI ELECTRIC CORPORATION**, Tokyo (JP)

JP 1582475 S 7/2017

(\*\*) Term: **15 Years**

*Primary Examiner* — T Chase Nelson

*Assistant Examiner* — Ania Aman

(21) Appl. No.: **29/656,364**

(74) *Attorney, Agent, or Firm* — Fitch, Even, Tabin & Flannery, LLP

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(57) **CLAIM**

The ornamental design for an electric furnace for substrate processing apparatus, as shown and described.

(30) **Foreign Application Priority Data**

**DESCRIPTION**

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(51) **LOC (12) Cl.** ..... **23-03**

(52) **U.S. Cl.**  
USPC ..... **D23/329**

(58) **Field of Classification Search**  
USPC ..... D23/314, 318, 319, 323, 329, 341;  
D13/112, 179; D15/144, 144.1, 144.2  
CPC ..... H01L 21/67109; H01L 21/67098; H01L  
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See application file for complete search history.

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FIG. 1 is a front, bottom and left side perspective view of an electric furnace for substrate processing apparatus showing our new design;

FIG. 2 is a front elevational view thereof;

FIG. 3 is a right side elevational view thereof;

FIG. 4 is a left side elevational view thereof;

FIG. 5 is a rear elevational view thereof;

FIG. 6 is a top plan view thereof;

FIG. 7 is a bottom plan view thereof.

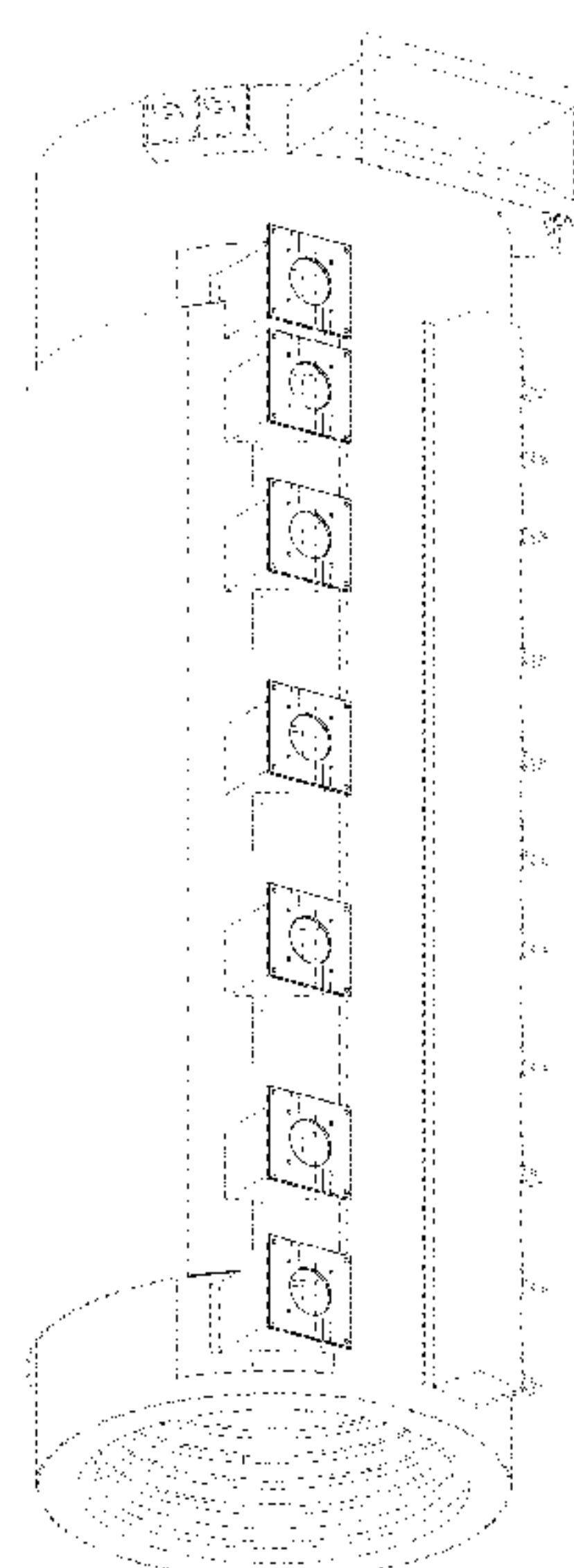
FIG. 8 is a cross-sectional view take along line 8-8 in FIG. 2 thereof; and,

FIG. 9 is an enlarged portion view taken along line 9-9 in FIG. 2.

The dashed-dot-dashed lines represent the boundary lines of the claimed design.

The broken lines shown in the drawings represent portions of the electric furnace for substrate processing apparatus that form no part of the claimed design.

**1 Claim, 8 Drawing Sheets**



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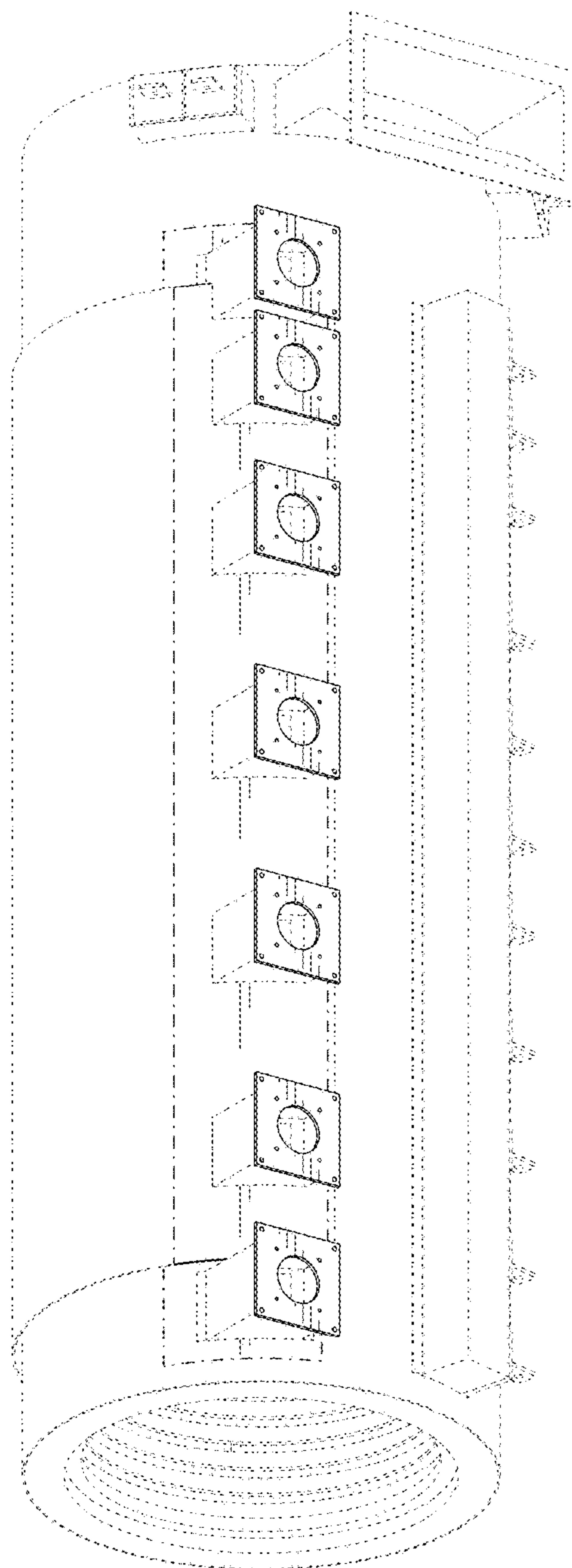


FIG. 1

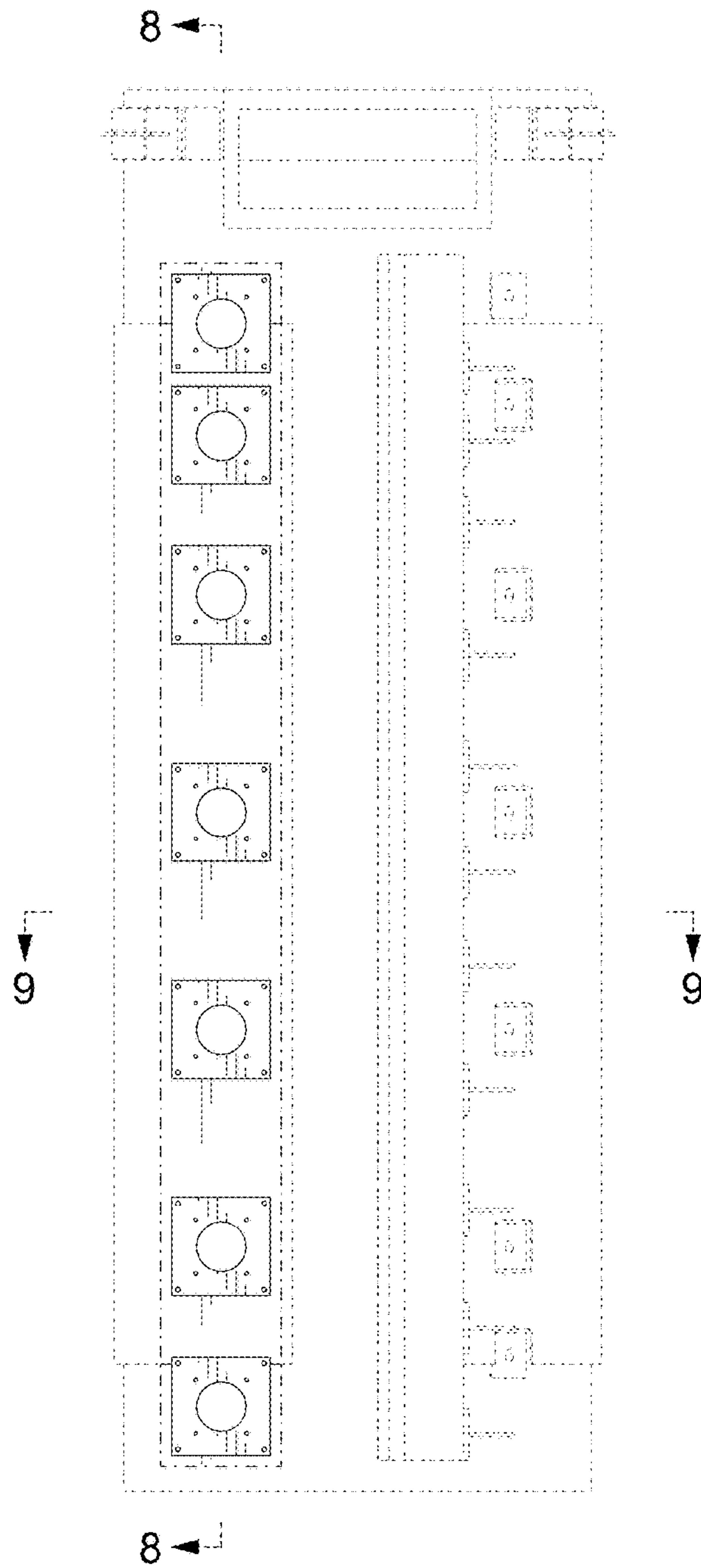


FIG. 2

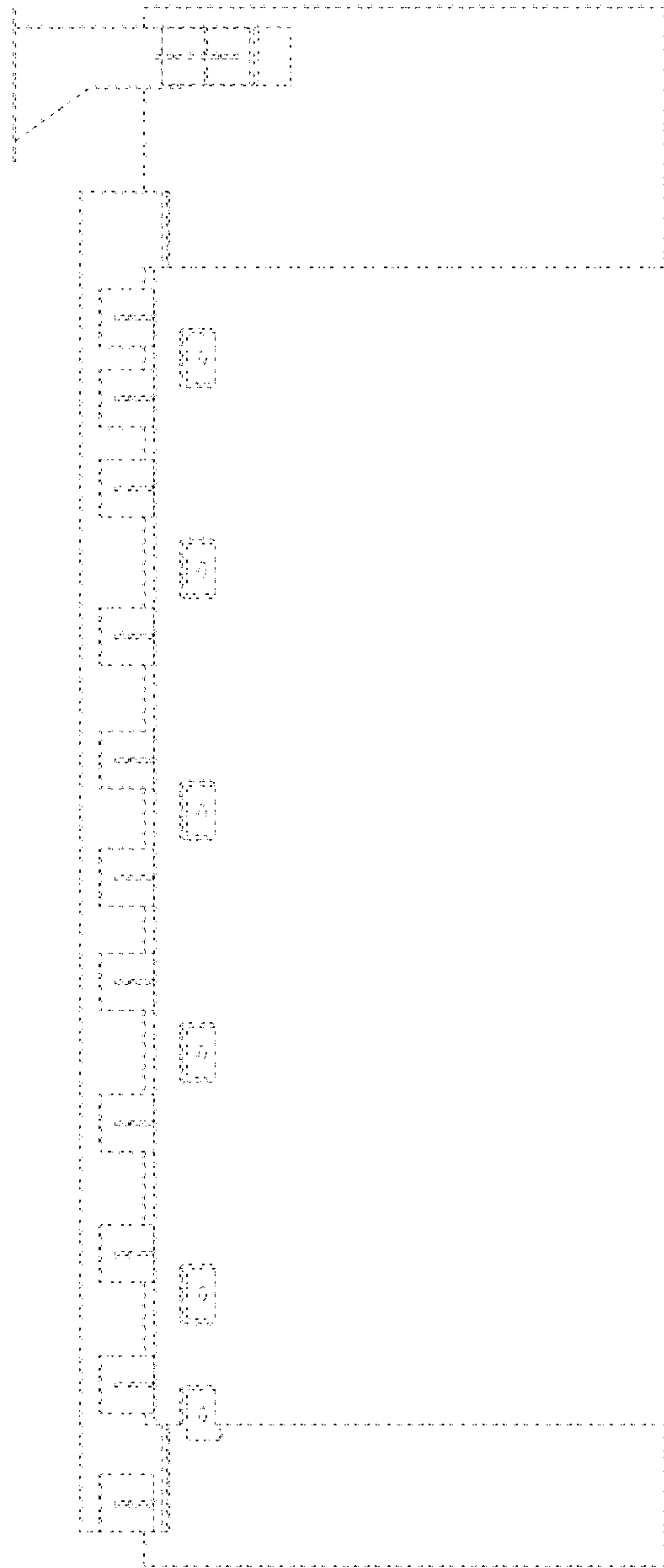


FIG. 3

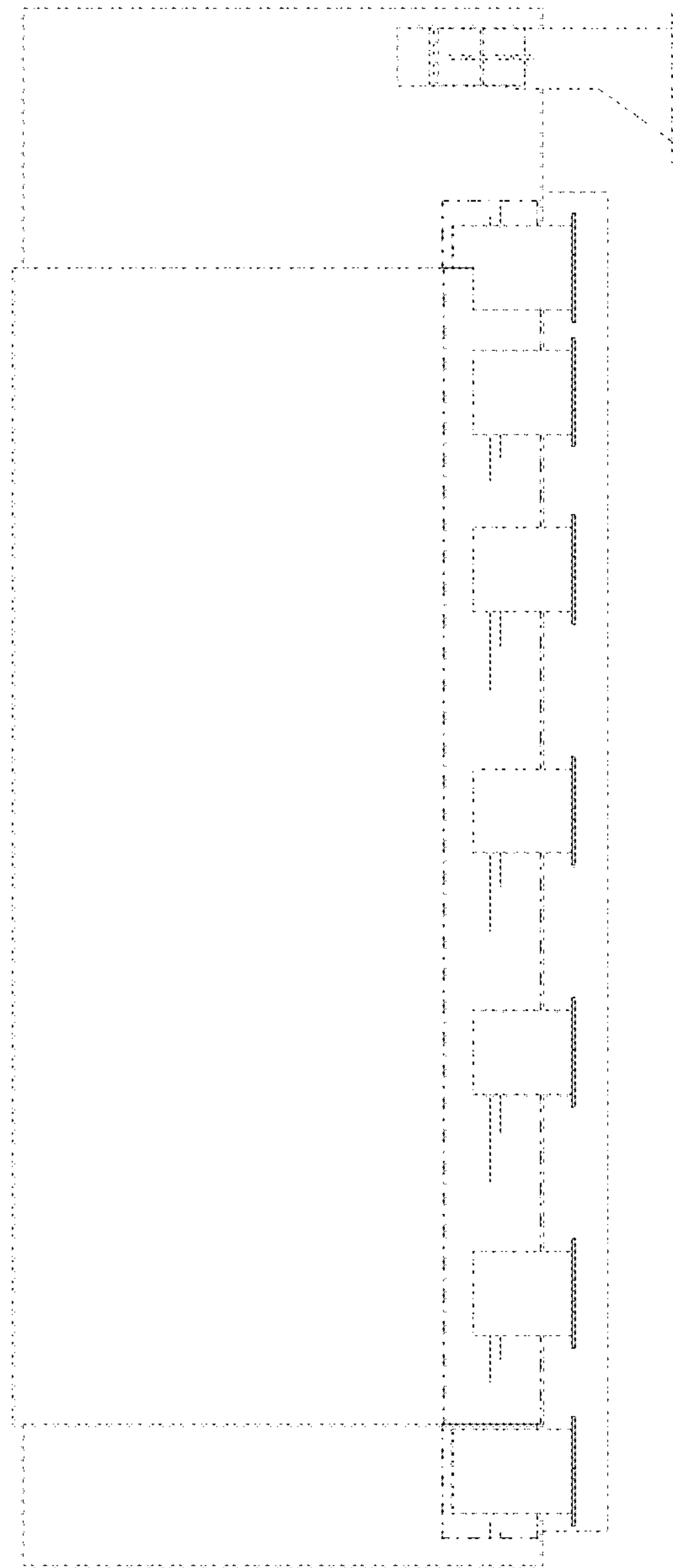


FIG. 4



FIG. 5

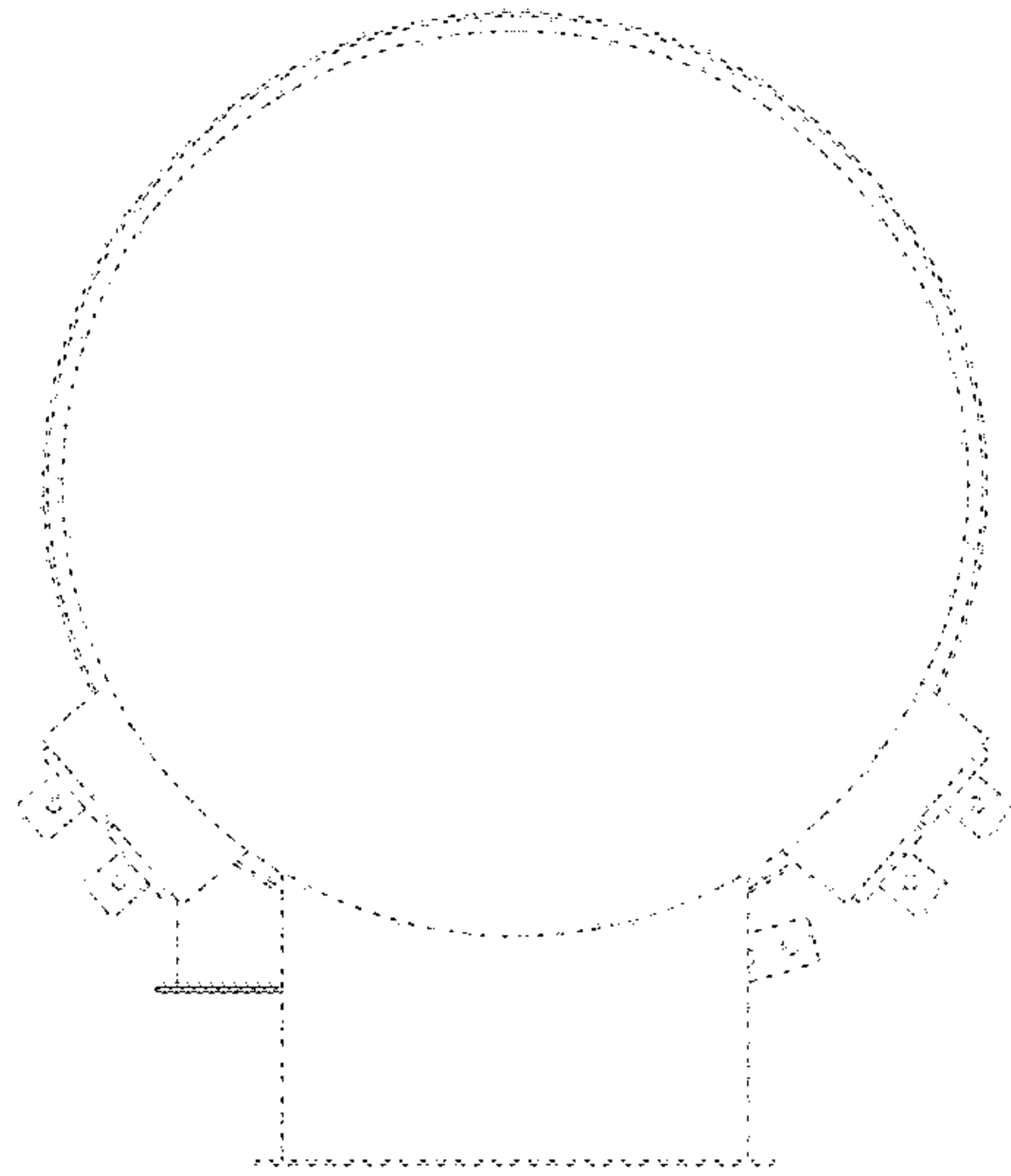


FIG. 6

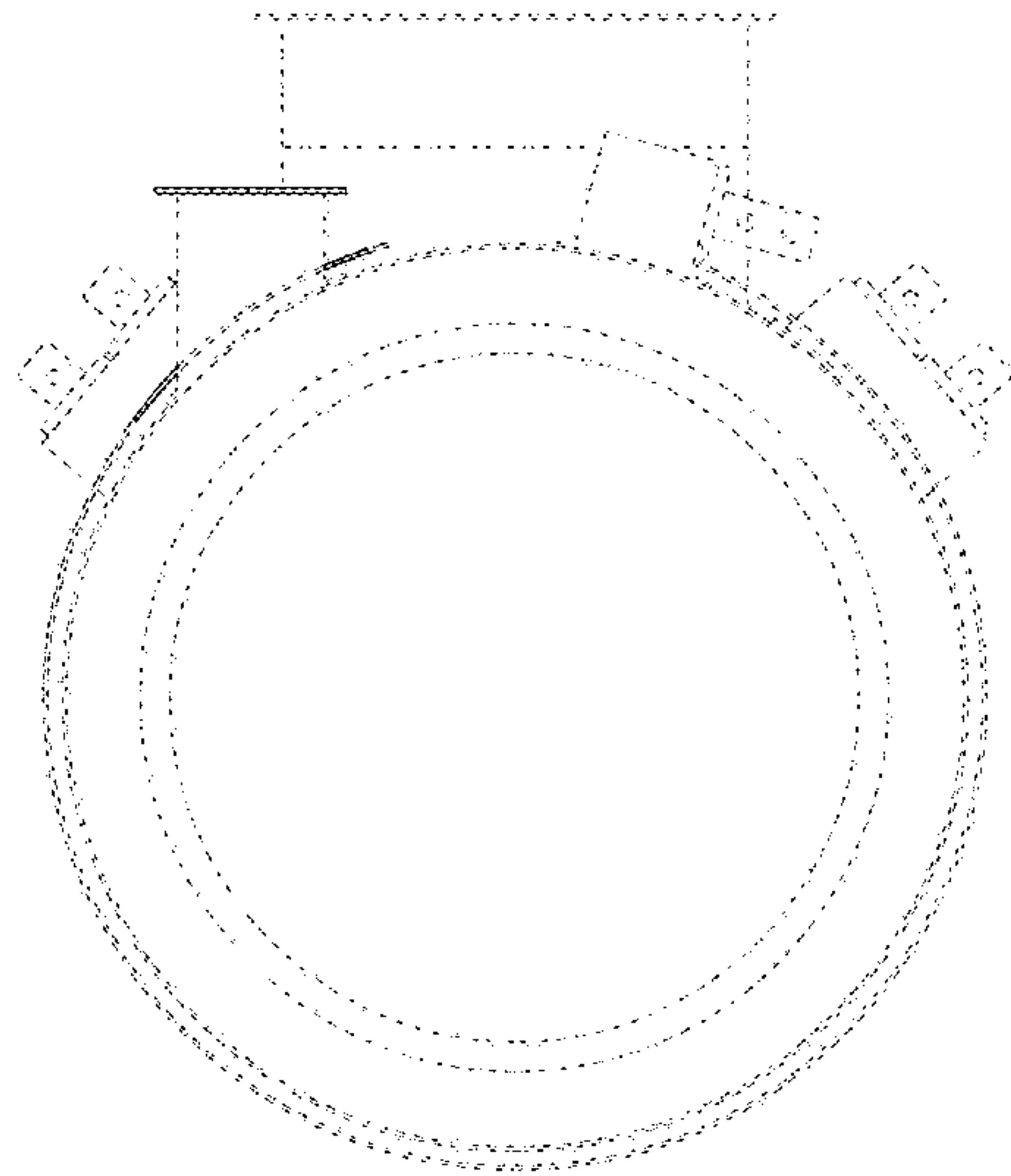


FIG. 7



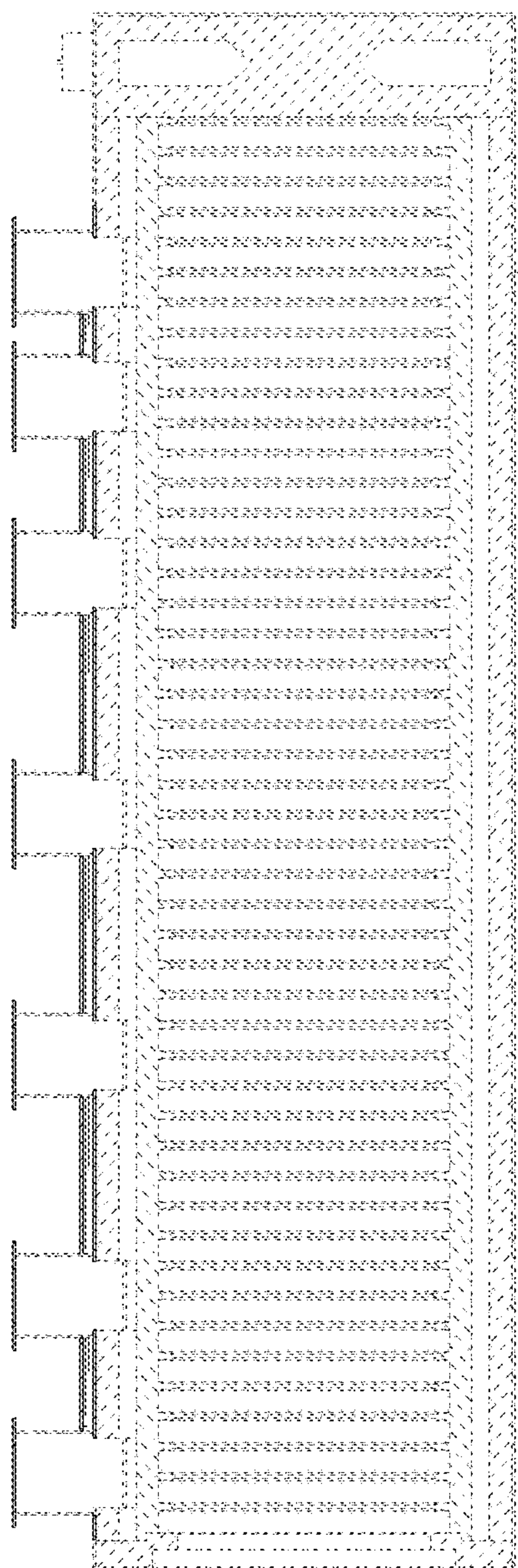


FIG. 8

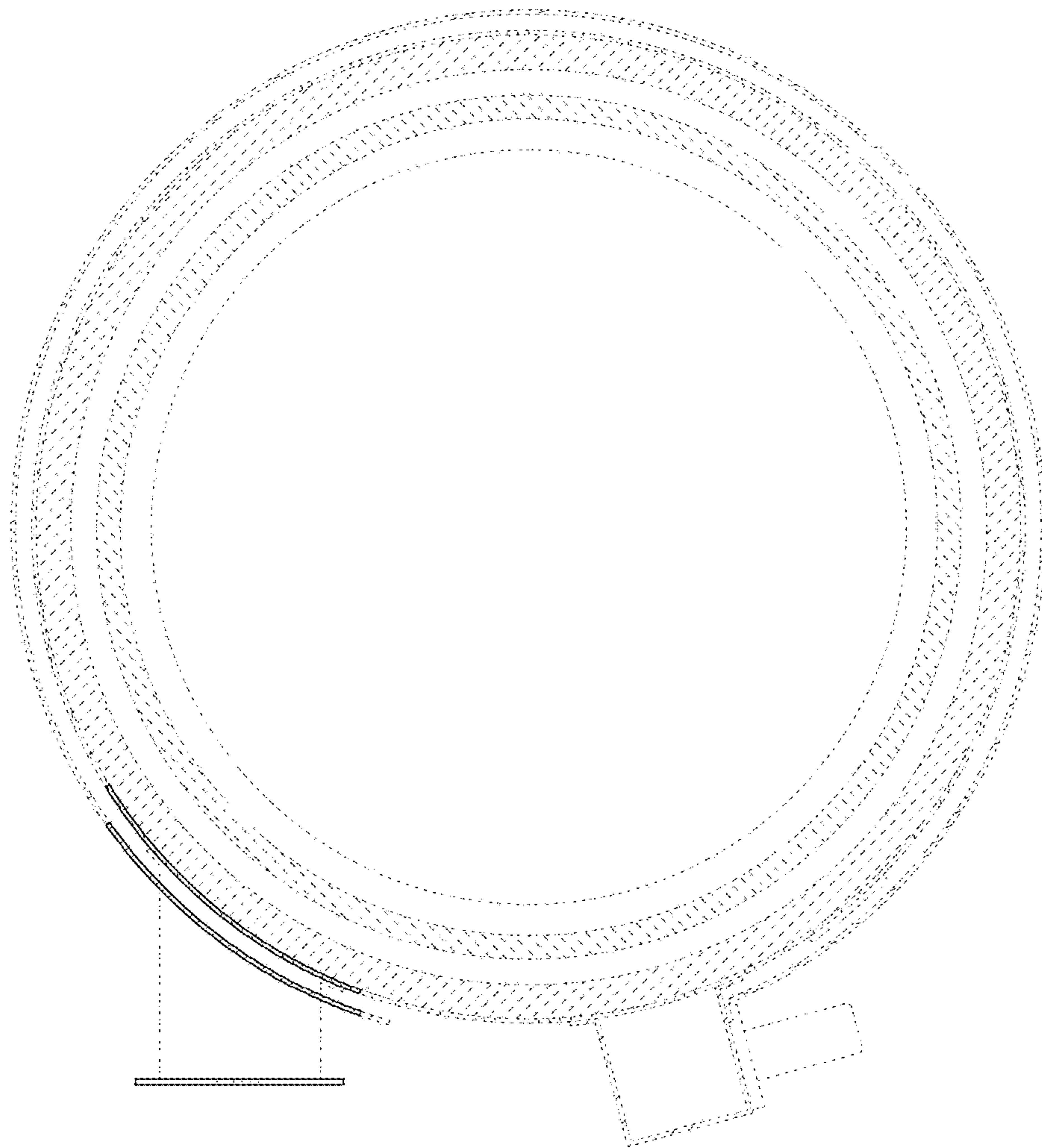


FIG. 9